

	L #	Hits	Search Text	DBs	Time Stamp
1	L1	2	("20040258930").PN. <i>pre-pub</i>	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	2006/09/06 12:05
2	L2	0	L1 and "factor of one"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2006/09/06 12:06
3	L3	1	L1 and factor	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2006/09/06 12:06

*finding support
for claim
10/602,266*

	L #	Hits	Search Text	DBs	Time Stamp
1	L1	65	(("6770515") or ("6927107") or ("6607971") or ("6939754") or ("6580053") or ("6830965") or ("6573163") or ("6495405") or ("6686978") or ("6635555") or ("6664147") or ("6645454") or ("6900083") or ("6809801") or ("6733931") or ("7087964") or ("6590228") or ("6818484") or ("6921434") or ("6903370") or ("6727125") or ("6607971") or ("6642092") or ("6777276") or ("6709910") or ("6913649") or ("6765249") or ("7018468") or ("6881686") or ("6995053") or ("7029961") or ("7056843")) .PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	2006/09/06 17:29

10/602,266 from Inventor
Name Search

Day : Wednesday

Date: 9/6/2006

Time: 15:42:24

PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = MORIGUCHI

First Name = MASAO

Application#	Patent#	Status	Date Filed	Title	Inventor Name
09660516	6770515	150	09/12/2000 ?	SEMICONDUCTOR DEVICE AND METHOD FOR FABRICATING THE DEVICE	MORIGUCHI, MASAO
09667527	6927107	150	09/22/2000 ?	METHOD OF PRODUCING SEMICONDUCTOR DEVICE	MORIGUCHI, MASAO
10136676	6607971	150	04/30/2002 X	METHOD FOR EXTENDING A LASER ANNEALING PULSE	MORIGUCHI, MASAO
10602266	Not Issued	30	06/23/2003	Grain-free polycrystalline silicon and a method for producing same	MORIGUCHI, MASAO
10640771	6939754	150	08/13/2003 X?	ISOTROPIC POLYCRYSTALLINE SILICON AND METHOD FOR PRODUCING SAME	MORIGUCHI, MASAO
10953938	Not Issued	41	09/28/2004 X	System and method for hydrogen exfoliation	MORIGUCHI, MASAO
11086680	Not Issued	30	03/23/2005 ?	Semiconductor substrate, semiconductor device, and manufacturing methods for them	MORIGUCHI, MASAO
11088252	Not Issued	30	03/24/2005 ?	Semiconductor device, producing method of semiconductor substrate, and producing method of semiconductor device	MORIGUCHI, MASAO
11099198	Not Issued	30	04/04/2005 ?	Isotropic polycrystalline silicon	MORIGUCHI, MASAO
11199166	Not Issued	30	08/09/2005 ?	Method for fabricating semiconductor device and semiconductor device	MORIGUCHI, MASAO

Inventor Search Completed: No Records to Display.

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MORIGUCHI	MASAO	Search

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PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = VOUTSAS

First Name = APOSTOLOS

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<u>09576939</u>	6432804	150	05/22/2000 X	SPUTTERED SILICON TARGET FOR FABRICATION OF POLYSILICON THIN FILM TRANSISTORS	VOUTSAS, APOSTOLOS
<u>09576940</u>	6429097	150	05/22/2000 X	APPARATUS AND METHOD TO SPUTTER SILICON FILMS	VOUTSAS, APOSTOLOS
<u>09653484</u>	6580053	150	08/31/2000 →	APPARATUS TO CONTROL THE AMOUNT OF OXYGEN INCORPORATED INTO POLYCRYSTALLINE SILICON FILM DURING EXCIMER LASER PROCESSING OF SILICON FILMS	VOUTSAS, APOSTOLOS
09696792	Not Issued	164	10/25/2000	Method of producing a cleaner silicon film	VOUTSAS, APOSTOLOS
<u>09696813</u>	6830965	150	10/25/2000 ?	SEMICONDUCTOR DEVICE AND A METHOD OF CREATING THE SAME UTILIZING METAL INDUCED CRYSTALLIZATION WHILE SUPPRESSING PARTIAL SOLID PHASE CRYSTALLIZATION	VOUTSAS, APOSTOLOS
09774270	Not Issued	164	01/29/2001	MASK PATTERN DESIGN TO IMPROVE QUALITY UNIFORMITY IN LATERAL LASER CRYSTALLIZED POLY-SI FILMS	VOUTSAS, APOSTOLOS
<u>09774290</u>	6573163	150	01/29/2001 ★	METHOD OF OPTIMIZING CHANNEL CHARACTERISTICS USING MULTIPLE MASKS TO FORM LATERALLY CRYSTALLIZED ELA POLY-SI FILMS	VOUTSAS, APOSTOLOS

<u>09774296</u>	<u>6495405</u>	150	01/29/2001	METHOD OF OPTIMIZING CHANNEL CHARACTERISTICS USING LATERALLY-CRYSTALLIZED ELA POLY-SI FILMS	VOUTSAS, APOSTOLOS
<u>09796330</u>	<u>6686978</u>	150	02/28/2001	METHOD OF FORMING AN LCD WITH PREDOMINANTLY <100> POLYCRYSTALLINE SILICON REGIONS	VOUTSAS, APOSTOLOS
09796341	Not Issued	162	02/28/2001	METHOD OF FORMING PREDOMINANTLY <100> POLYCRYSTALLINE SILICON THIN FILM TRANSISTORS	VOUTSAS, APOSTOLOS
<u>09796345</u>	<u>6635555</u>	150	02/28/2001	METHOD OF CONTROLLING CRYSTALLOGRAPHIC ORIENTATION IN LASER-ANNEALED POLYCRYSTALLINE SILICON FILMS	VOUTSAS, APOSTOLOS
<u>09796927</u>	<u>6664147</u>	150	02/28/2001	METHOD OF FORMING THIN FILM TRANSISTORS ON PREDOMINANTLY <100> POLYCRYSTALLINE SILICON FILMS	VOUTSAS, APOSTOLOS
<u>09862092</u>	<u>6649032</u>	150	05/21/2001	SYSTEM AND METHOD FOR SPUTTERING SILICON FILMS USING HYDROGEN GAS MIXTURES	VOUTSAS, APOSTOLOS
<u>09862107</u>	<u>6673220</u>	150	05/21/2001	SYSTEM AND METHOD FOR FABRICATING SILICON TARGETS	VOUTSAS, APOSTOLOS
<u>09881390</u>	<u>6623653</u>	150	06/12/2001	SYSTEM AND METHOD FOR ETCHING ADJOINING LAYERS OF SILICON AND INDIUM TIN OXIDE	VOUTSAS, APOSTOLOS
09893866	Not Issued	163	06/28/2001	Method for forming silicon films with trace impurities	VOUTSAS, APOSTOLOS
09894349	Not Issued	161	06/28/2001	Pulse width method for controlling lateral growth in crystallized silicon films	VOUTSAS, APOSTOLOS
<u>09894940</u>	<u>6645454</u>	150	06/28/2001	SYSTEM AND METHOD FOR REGULATING LATERAL GROWTH IN LASER IRRADIATED SILICON FILMS	VOUTSAS, APOSTOLOS
<u>09906881</u>	<u>6579425</u>	150	07/16/2001	SYSTEM AND METHOD FOR FORMING BASE COAT AND	VOUTSAS, APOSTOLOS

				THIN FILM LAYERS BY SEQUENTIAL SPUTTER DEPOSITING	
09945063	6900083	150	08/31/2001	METHOD OF FORMING MULTI-LAYERS FOR A THIN FILM TRANSISTOR (TFT) AND THE DEVICE FORMED THEREBY	VOUTSAS, APOSTOLOS
10095987	6809801	150	03/11/2002	1:1 PROJECTION SYSTEM AND METHOD FOR LASER IRRADIATING SEMICONDUCTOR FILMS	VOUTSAS, APOSTOLOS
10096293	6660576	150	03/11/2002	SUBSTRATE AND METHOD FOR PRODUCING VARIABLE QUALITY SUBSTRATE MATERIAL	VOUTSAS, APOSTOLOS
10099376	6733931	150	03/13/2002	SYMMETRICAL MASK SYSTEM AND METHOD FOR LASER IRRADIATION	VOUTSAS, APOSTOLOS
10213815	Not Issued	161	08/06/2002	Devices fabricated using apparatus to sputter silicon films	VOUTSAS, APOSTOLOS
10213816	6789499	150	08/06/2002	APPARATUS TO SPUTTER SILICON FILMS	VOUTSAS, APOSTOLOS
10218744	6717178	150	08/13/2002	SEMICONDUCTOR DEVICES FABRICATED USING SPUTTERED SILICON TARGETS	VOUTSAS, APOSTOLOS
10253806	7087964	150	09/23/2002	PREDOMINANTLY <100> POLYCRYSTALLINE SILICON THIN FILM TRANSISTOR	VOUTSAS, APOSTOLOS
10256360	6590228	150	09/26/2002	LCD DEVICE WITH OPTIMIZED CHANNEL CHARACTERISTICS	VOUTSAS, APOSTOLOS
10280990	6818484	150	10/24/2002	METHOD OF FORMING PREDOMINANTLY <100> POLYCRYSTALLINE SILICON THIN FILM TRANSISTORS	VOUTSAS, APOSTOLOS
10345724	Not Issued	161	01/15/2003	Laser annealing apparatus to control the amount of oxygen incorporated into polycrystalline silicon films	VOUTSAS, APOSTOLOS
10384888	Not Issued	71	03/10/2003	Pulse width method for controlling lateral growth in crystallized silicon films	VOUTSAS, APOSTOLOS
10678575	6921434	150	10/03/2003	REGULATED GROWTH METHOD FOR LASER	VOUTSAS, APOSTOLOS

No

				IRRADIATING SILICON FILMS	
<u>10704928</u>	Not Issued	30	11/10/2003	Silicon film for <u>thin</u> film transistors	VOUTSAS, APOSTOLOS
<u>10705279</u>	<u>6903370</u>	150	11/10/2003 ?	VARIABLE QUALITY SEMICONDUCTOR FILM SUBSTRATE	VOUTSAS, APOSTOLOS
<u>10749060</u>	<u>6878640</u>	150	12/30/2003 X	METHOD FOR FABRICATING SILICON TARGETS	VOUTSAS, APOSTOLOS
<u>10113144</u>	<u>6792029</u>	150	03/27/2002 X	METHOD OF SUPPRESSING ENERGY SPIKES OF A PARTIALLY-COHERENT BEAM	VOUTSAS, APOSTOLOS T.
<u>10124826</u>	Not Issued	90	04/17/2002	LASER ANNEALING MASK AND METHOD FOR SMOOTHING AN ANNEALED SURFACE	VOUTSAS, APOSTOLOS T.
<u>10124853</u>	<u>6727125</u>	150	04/17/2002	MULTI-PATTERN SHADOW MASK SYSTEM AND METHOD FOR LASER ANNEALING	VOUTSAS, APOSTOLOS T.
<u>10136676</u>	<u>6607971</u>	150	04/30/2002	METHOD FOR EXTENDING A LASER ANNEALING PULSE	VOUTSAS, APOSTOLOS T.
<u>10194895</u>	<u>6642092</u>	150	07/11/2002	THIN-FILM TRANSISTORS FORMED ON A METAL FOIL SUBSTRATE	VOUTSAS, APOSTOLOS T.
<u>10232089</u>	<u>6777276</u>	150	08/29/2002	SYSTEM AND METHOD FOR OPTIMIZED LASER ANNEALING SMOOTHING MASK	VOUTSAS, APOSTOLOS T.
<u>10273549</u>	<u>6709910</u>	150	10/18/2002 X X	SYSTEM AND METHOD FOR REDUCING SURFACE PROTRUSIONS IN THE FABRICATION OF LILAC SILICON FILMS	VOUTSAS, APOSTOLOS T.
<u>10282744</u>	<u>6911666</u>	150	10/28/2002 X	FLEXIBLE METAL FOIL SUBSTRATE DISPLAY AND METHOD FOR FORMING SAME	VOUTSAS, APOSTOLOS T.
<u>10602186</u>	<u>6913649</u>	150	06/23/2003 ?	SYSTEM AND METHOD FOR FORMING SINGLE-CRYSTAL DOMAINS USING CRYSTAL SEEDS	VOUTSAS, APOSTOLOS T.
<u>10602266</u>	Not Issued	30	06/23/2003	Grain-free polycrystalline silicon and a method for producing same	VOUTSAS, APOSTOLOS T.

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10621845	<u>6765249</u>	150	07/16/2003	THIN-FILM TRANSISTORS FORMED ON A FLEXIBLE SUBSTRATE	VOUTSAS, APOSTOLOS T.
<u>10640771</u>	6939754	150	08/13/2003	ISOTROPIC POLYCRYSTALLINE SILICON AND METHOD FOR PRODUCING SAME	VOUTSAS, APOSTOLOS T.
10655700	Not Issued	161	09/05/2003	Thin-film transistors on a flexible substrate	VOUTSAS, APOSTOLOS T.
<u>10713383</u>	<u>7018468</u>	150	11/13/2003	PROCESS FOR LONG CRYSTAL LATERAL GROWTH IN SILICON FILMS BY UV AND IR PULSE SEQUENCING	VOUTSAS, APOSTOLOS T.
<u>10755487</u>	Not Issued	71	01/12/2004	Thin film structure from LILAC annealing	VOUTSAS, APOSTOLOS T.

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Inventor Name Search Result

Your Search was:

Last Name = VOUTSAS

First Name = APOSTOLOS

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<u>10801374</u>	7087537	150	03/15/2004 X	METHOD FOR FABRICATING OXIDE THIN FILMS	VOUTSAS, APOSTOLOS T.
<u>10805120</u>	6881686	150	03/19/2004 P	LOW-FLUENCE IRRADIATION FOR LATERAL CRYSTALLIZATION ENABLED BY A HEATING SOURCE	VOUTSAS, APOSTOLOS T.
<u>10812591</u>	Not Issued	95	03/29/2004 P	HIGH DENSITY PLASMA PROCESS FOR THE FORMATION OF SILICON DIOXIDE ON SILICON CARBIDE SUBSTRATES	VOUTSAS, APOSTOLOS T.
<u>10831424</u>	6995053	150	04/23/2004 ?	VERTICAL THIN FILM TRANSISTOR	VOUTSAS, APOSTOLOS T.
<u>10831443</u>	Not Issued	41	04/23/2004 ?	Multi-pattern shadow mask system for laser annealing	VOUTSAS, APOSTOLOS T.
<u>10831671</u>	Not Issued	83	04/23/2004 ?	Multi-pattern shadow mask laser annealing system	VOUTSAS, APOSTOLOS T.
<u>10862761</u>	Not Issued	71	06/07/2004	Multi-planar layout vertical thin- film transistor inverter	VOUTSAS, APOSTOLOS T.
<u>10871939</u>	Not Issued	41	06/17/2004 X	High density plasma process for silicon thin films	VOUTSAS, APOSTOLOS T.
<u>10883381</u>	7046715	150	07/01/2004 X	METHOD FOR SUPPRESSING ENERGY SPIKES OF A PARTIALLY-COHERENT BEAM USING TRIANGULAR END-REGIONS	VOUTSAS, APOSTOLOS T.
<u>10897763</u>	6959029	150	07/22/2004 P	APPARATUS FOR PERFORMING ANASTOMOSIS	VOUTSAS, APOSTOLOS T.
<u>10913678</u>	7029961	150	08/05/2004	METHOD FOR OPTIMIZED LASER ANNEALING SMOOTHING	VOUTSAS, APOSTOLOS T.

10953913	Not Issued	161	09/28/2004	Dual-gate thin-film transistor	VOUTSAS, APOSTOLOS T.
10985587	Not Issued	30	11/09/2004	Simultaneous planar and non-planar thin-film transistor processes	VOUTSAS, APOSTOLOS T.
11013605	Not Issued	30	12/15/2004	High-density plasma hydrogenation	VOUTSAS, APOSTOLOS T.
11031316	Not Issued	30	01/05/2005	Method for forming a flexible metal foil substrate display	VOUTSAS, APOSTOLOS T.
11062068	7056843	150	02/18/2005	LOW-FLUENCE IRRADIATION FOR LATERAL CRYSTALLIZATION ENABLED BY A HEATING SOURCE	VOUTSAS, APOSTOLOS T.
11099198	Not Issued	30	04/04/2005	Isotropic polycrystalline silicon	VOUTSAS, APOSTOLOS T.
11101741	Not Issued	30	04/07/2005	Structures with seeded single-crystal domains	VOUTSAS, APOSTOLOS T.
11139726	Not Issued	30	05/26/2005	High-density plasma oxidation for enhanced gate oxide performance	VOUTSAS, APOSTOLOS T.
11184699	Not Issued	20	07/18/2005	Dual-gate transistor display	VOUTSAS, APOSTOLOS T.
11218111	Not Issued	30	09/01/2005	High density plasma grown silicon nitride	VOUTSAS, APOSTOLOS T.
11261194	Not Issued	30	10/28/2005	Thin-film transistor with vertical channel region	VOUTSAS, APOSTOLOS T.
11263604	Not Issued	20	10/31/2005	Pulse sequencing lateral growth method	VOUTSAS, APOSTOLOS T.
11264979	Not Issued	30	11/02/2005	High-density plasma multilayer gate oxide	VOUTSAS, APOSTOLOS T.
11327612	Not Issued	30	01/06/2006	Enhanced thin-film oxidation process	VOUTSAS, APOSTOLOS T.
11387626	Not Issued	20	03/23/2006	Two-transistor tri-state inverter	VOUTSAS, APOSTOLOS T.
11408220	Not Issued	30	04/20/2006	Four-transistor Schmitt trigger inverter	VOUTSAS, APOSTOLOS T.
11418273	Not Issued	30	05/04/2006	Silicon oxide thin-films with embedded nanocrystalline silicon	VOUTSAS, APOSTOLOS T.
11439410	Not Issued	20	05/23/2006	Digital-to-time converter	VOUTSAS, APOSTOLOS T.
11479221	Not Issued	30	06/30/2006	Sidewall gate thin-film transistor	VOUTSAS, APOSTOLOS T.

08928600	5994156	150	09/12/1997	METHOD OF MAKING GATE AND SOURCE LINES IN TFT LCD PANELS USING PURE ALUMINUM METAL	VOUTSAS, APOSTOLOS T.
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